

--ABSTRACT OF THE DISCLOSURE

*Check B10*

A lithographic projection apparatus is presented. The projection apparatus includes an intermediate table on which a substrate can be positioned before transfer to the substrate table. The intermediate table includes a major surface provided with a plurality of apertures and a gas bearing generator which generates a gas bearing between the major surface of the intermediate table and the substrate.--

006T40"22925560

## ABSTRACT:

"Lithographic Projection Apparatus"

5 A lithographic projection apparatus, comprising:  
a radiation system for supplying a projection beam of radiation;  
a mask table provided with a mask holder for holding a mask;  
a substrate table provided with a substrate holder for holding a substrate;  
a projection system for imaging an irradiated portion of the mask onto a target  
portion of the substrate; and  
a preparatory station comprising an intermediate table 5 on which a substrate 1  
can be positioned before transfer to the substrate table;  
10 characterized in that the intermediate table 5 comprises a major surface 11  
provided with a plurality of apertures 9, and gas bearing means for generating a gas bearing  
between said major surface 11 and a substrate 1 located thereon.

Fig. 2a

09/552672, 041900